

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Blaine R. Spady; John D. Heaton; Robert Buchanan; Richard A. Yarussi
(as amended)
Assignee: Nanometrics Incorporated
Title: Metrology/Inspection Positioning System
Serial No.: 09/458,123 Filing Date: December 8, 1999
Examiner: Gordon Stock Group Art Unit: 2877
Docket No.: NAN035 US Confirmation No.: 8470

Santa Clara, California
August 4, 2006

Mail Stop RCE
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

This Amendment is filed with a Request for Continued Examination, a substitute specification, amended drawings, and a Request for Correction of Inventorship. Please enter the following amendments before taking action on the merits of the above-referenced application.

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